

Receipt is hereby acknowledged for the following in the U.S. Patent and Trademark Office

Applicant: Cyrille, et al.
For: METHOD FOR PROVIDING A LIFTOFF PROCESS USING A
SINGLE LAYER RESIST AND CHEMICAL MECHANICAL
POLISHING AND SENSOR FORMED THEREWITH
Serial No.: 10/633,765
Filing Date: 08/04/2003
Date of Deposit: May 1, 2006
Docket No.: HSJ9 2003-0027US1 (0518)

RECEIVED THIS DATE:

- ☒ Transmittal Letter
- ☒ Part B Fee Transmittal
- ☒ Fee Address Indication Form
- ☒ Return Postcard

